

ABSTRACT

A meshed etching tunnel made of aluminum is disposed inside a cylindrical quartz reactive chamber, and speaker diaphragms are aligned inside the tunnel at a certain interval. Opposing electrodes are disposed outside the reactive chamber. Plasma is applied at low temperature to prevent heat deformation. Uniform wettability is also assured by the use of the meshed etching tunnel, achieving high productivity. Uniform wettability further stabilizes bonding and improves bonding strength of the speaker diaphragm onto the voice coil and edge, offering a speaker with improved input power durability.